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Docket No.: SON-2769  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Hidetoshi Ohnuma

Application No.: 10/603,689

Filed: June 26, 2003

Conf. No. 2872  
Examiner: Saleha R. Mohamedulla

Group Art: 1756

For: EXPOSURE METHOD, MASK  
FABRICATION METHOD, FABRICATION  
METHOD OF SEMICONDUCTOR DEVICE,  
AND EXPOSURE APPARATUS

**STATUS INQUIRY**

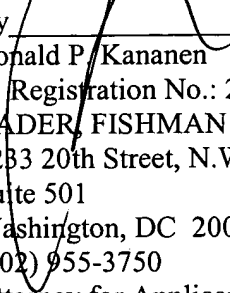
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

It is respectfully requested that the attorney named below be advised of the status of the above-identified application. Specifically, please advise us of when an initial Office Action on the merits may be expected from the Patent and Trademark Office. The application has now been pending approximately 20 months without an action on the merits.

Dated: February 22, 2005

Respectfully submitted,

By   
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